	Hits	Search Text	DBs	Time Stamp
1	742	scanning with mask with light with pattern	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2008/01/22 11:15
2	364	scanning with mask with light with pattern same substrate	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2008/01/22 11:17
3	159	scanning with mask with light with pattern same substrate and scanning with perpendicular	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2008/01/22 11:17
4	2	scanning with mask with light with pattern with (forming form formed) same substrate and scanning with perpendicular and data adj line	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2008/01/22 11:20
5	108	scanning with mask with light with pattern with (forming form formed) same substrate and scanning with perpendicular	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2008/01/22 11:19
6	63	scanning with mask with light with pattern with (forming form formed) same substrate and scanning with perpendicular and substrate with (photoresist resist)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2008/01/22 11:27